



PRESTANDARDIZATION STUDY ON THE CHARACTERIZATION OF AIRBORNE NANOPARTICLES SIZE:

Size characterization of airborne SiO₂ nanoparticles with on-line and off-line measurement techniques: validation with an interlaboratory comparison

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Context



- Production and use of manufactured nanoparticles, nano-objects, nanostructured powders and nanomaterials (I SO/TS 80004-1:2010) in ≠ forms (TiO₂, SiO₂, NTC, Ag, Al₂O₃,...) by industry and research laboratories
 - ≠ Applications : environnement, energie, electronics, cosmetics, car industry construction, medicine, bio-technology, food...



Context



Potential Risks: General population, Environment and product



Human protection



Atmospheric measurement



Process and workers

Need to have some airborne NP characterization metrological standard procedures

• To curb to reliable toxicology studies and ecotoxicology, quality control in industry, the monitoring, the reglementation which begin to arrive now in France (Décret 2012-232 du 17 février 2012 et arrêté du 6 août 2012 relatifs à la déclaration annuelle des substances à l'état nanoparticulaire)





Objectives of VAMAS project



VAMAS : Versailles Project on Advanced Materials and Standards (1985)

An international collaborative organization on prestandardization research projects and specifications for advanced materials

Objectives

- To develop size characterization methods for airborne nanoparticles that include the entire measurement chain (sampling, analysis, data process) which are traceable and accurate including metrological traceability, calibration, and evaluation of the measurement uncertainty.
- Validated the developed protocols by an interlaboratory comparison based on metrological approaches

Organisation

- The study performed within the framework of the Technical Working Area (TWA) 34 -"Properties of Nanoparticle Populations" of the VAMAS in the project n°3 "Techniques for characterizing size distribution of airborne nanoparticles"
- Mai 2009 septembre 2012
- > <u>Participants</u> :
 - LNE : leader du projet
 - 12 national Metrology Institutes : BAM (Germany), CENAM (Mexico), DFM (Denmark), NMIA (Australia), NMISA (South Africa), INPL (Israel), KRISS (South Korea), LNE (France), NIST (USA), NPL (UK), NMIJ-AIST (Japan) and NPLI (India)
 - 6 laboratories involved in nanoparticle metrology : LPMA (France), LISA (France), ILAQH -SEF (Australia), UNC (Israel) and UNIGE (Italy)



Work plan: project in 3 phases





- Phase 2: Mai 2011 April 2012
- Evaluation of protocols developped
- Interlaboratory comparison with on-line (SMPS) and off-line (AFM, MEB et TEM)

measurement techniques

Phase 3: Mai 2011 – September 2012

- Analyse of results and validation of protocols

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Project description



PSL (CRM) for SMPS calibration



Generation of nanoaerosols + On-line Measurement (1/2)

Using of Scanning Mobility Particle Sizer (SMPS)



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Le progrès, une possion à partag

Generation of nanoaerosols + On-line measurement (1/2) LNE

- Preparation of colloïdales suspensions :
 - 2 manufactured colloïdales suspensions diluted with Milli-Q water in order to obtain 2 types of non-agglomerated nano-aerosols (1) a monodisperse population called "Aerosol One Population" (aerosol OP). (2) two nanoparticle populations (a bimodal PSD) called "Aerosol Double Population" (aerosol DP) of isolated (no-agglomerated) airborne particles
- Generation :
 - Cleaning procedure
 - Analyse of background
 - P = 2.4 bar with atomiser
- Measurement : SMPS
 - Scanning mode (Commercial software AIM)
 - Stepping mode (DMA moment method) with same DMA (3080, TSI)
- > Traceability :
 - Calibration of DMA with PSL (CRMs) certified by TEM : 46 nm ± 2 nm, 81 nm ± 3 nm et 100.82 nm ± 0.66 nm (conpliant to the standard I SO 15900 "Determination of particle size distribution – Differential electrical mobility analysis for aerosol particles")
- Results treatement :
 - Using differents laws : gaussian (normal), asymmetric gaussian, and log-normal
 - Uncertainty evaluation : ISO 5725-2 (repeatability and reproducibility) et sources (# generators, DMA flow conditions, diffusion and charge corrections)



On-line measurement (SMPS): Results



32 nm < dp mean < 36 nm, except SMPS3 (43 nm)</p>

Laboratory

> SD repro $\leq 1 \text{ nm} / U(k=2) \leq 4 \text{ nm}$

Mean diameter d_m (nm)

- Influence of range used to determine the mean diameter (≠ of 2 nm for atomiseur and ≠ of 0,6 nm for electrospray)
- Incertainty stepping ≤ scanning

On-line measurement (SMPS): Results



- 1^{er} population : 39 nm < dp1 mean < 46 nm 2nd population : 82 nm < dp2 mean < 88 nm</p>
- > 1^{er} population : SD repro ≤ 2 nm / U(k=2) ≤ 13 nm 2^{eme} population : SD repro $\le 0,5$ nm / U(k=2) ≤ 4 nm
- Influence of range used to determine the mean diameter (# max of 5 nm)
 - **Ratios in number concentration** between the 2 populations: peak et area

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Off-line measurement: Sampling



Aerosol Inlet

Flov

Particle Stream

Sample Electrode

2 types of sampling methods + 3 supports types

- Polycarbonate membrane filter (PMF) 1 - Filtration (Diffusion-impaction-interception) - Grilles TEM deposited on PMF
- **MICA and TEM Grids** 2 - Electrostatic precipitation (NAS)
 - Sampling performed by 4 laboratories : \succ 4 types of samples :
 - Sample A (filtration + 2 TEM grids« G »)
 - Sample B (NAS + Grids « N1, N2, N3 et N4 »)
 - Sample C (filtration + PC alone « F1,F2 et F2 »)
 - Sample D (NAS + MICA « M1, M2 et M3 »)
 - Protocols of sampling \geq (scientific literature + consensus)

(Q, diameter of the filters and the pores, sampling time,...)





Protocols for storage conditions and sample transport

Part P₁ : for transfer on TEM grids (g1, g2) Part P₂ : used for SEM

d = 25 mm

TEM Grid

Polycarbona Membrane

Off-line measurement: Protocols AFM, SEM and TEM & LNE

Samples preparation :

Examples : - SEM with high-voltage : Coating - MET : Transfer of particles from PMF to TEM grids

Protocole de mesures :



Mesurand / Conditions of measurement / Materials / Traceability (CRM) / Number of measured particles :

Example for AFM: maximum particle height (Apex) / 2 CRM for the metrologic comparability (calibrated step height of 41.2 ± 0.7 nm and PSL with a mean calibrated diameter of 46 ± 2 nm certified by TEM) / scan range = 2 x 2 µm / image size: 512 x 512 pixels /Tapping or intermittent mode / Supersharp tips / Recommandation of a minimum of 400 measured particles per sampleper sample in order to allow a reasonable statistical evaluation of the PSD ...

Results treatement : I mages treatement

Measurement uncertainty evaluation :

Estimation by each participants in function of their measurement methods, data treatement and of their instrumentation : contribution of severeal sources

Example for SEM and TEM: correction or taken into account of the coating thickness, calibration of the magnification, threshold in the greyscale images.





Off-line measurement: AFM Results



Sampling laboratory SMPS4 SMPS2 SMPS3 100 90 卍 80 diameter (nm) 70 DP 60 50 Mean 40 φĀ ΤĄ 30 Averaged mean diamete 20 Averaged mean diameter ± 2 x SD Grid G 10 Grid N MICA M AFM1 AFM2 AFM1 AFM2 AFM3 AFM2

4 laboratories involved

- Good agreement between the results of different participants
 - 27 nm < dp mean < 33 nm, except AFM4 (35 nm)</p>
- > U (k=2) ≤ 7 nm / total mean average = 30.3 ± 3.7 nm
- No significant difference between the ≠ samples types (Samples A, B et D)
- The Lowest uncertainty obtained with MICA

- Good agreement between the results of different participants
- 1^{er} population : 32 nm < dp1 mean < 42 nm 2nd population : 78 nm < dp2 mean < 85 nm</p>
- ▶ U (k=2) \leq 5 nm for 1^{er} population and 2nd population
- Total mean averages = 36.2 ± 7.1 nm / 80.2± 5.0 nm
- Ratios in number concentration between the 2 populations: peak et area



Off-line measurement: TEM Results



7 laboratories involved





- 29 nm < dp mean < 39 nm, except for the g grids (transfer)
- > U (k=2) ≤ 5 nm / Total mean average = 35.1 ± 7.4 nm
- High difference between the grids G and g (17 nm): influence of transfer

For TEM, avoid to use the transfer of particles from filter to TEM and choose to use the direct deposition on grids: High impact on PSD

Off-line measurement: TEM Results



7 laboratories involved



TEM4 TEM3 TEM1 TEM5[|] TEM4 TEM1 TEM2 TEM 6 TEM7 [|] TEM5 TEM2[|] TEM3

- 1^{er} population : 35 nm < dp1 mean < 49 nm 2nd population : 77 nm < dp2 mean < 92 nm except for the g grids (transfer)</p>
- > $U \le 5$ nm for 1^{er} population and 2nd population
- Total mean average = 42.9 ± 9.0 nm / 86.3 ± 12.3 nm
- > Ratios in number concentration between the 2 populations: peak et area

Off-line measurement: SEM Results





7 laboratories involved

- ➢ 30 nm < dp mean < 51 nm</p>
- High dispersion of results : SD interlabo for SEM >> AFM and TEM
- > SD repro \leq 3 nm
- > U (k=2) ≤ 5 nm without coating U (k=2) ≤ 32 nm with coating
- Total mean average = 39.0 ± 14.2 nm



The Lowest uncertainties were obtained for the low-voltage SEM (without coating)

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Off-line measurement: SEM Results





7 laboratories involved



- 1^{er} population : 32 nm < dp1 mean < 58 nm 2nd population : 74 nm < dp2 mean < 102 nm</p>
- > SD repro \leq 7 nm for 1^{er} population and 2nd population except SEM2
- > $U(k=2) \le 5$ nm without coating U(k=2) ≤ 32 nm with coating

- For SEM , don't use coating : high impact on PSD and strong increase of measurement uncertainty
- Total mean averages = 46.6 ± 15.1 nm / 89.8 ± 20.4 nm
- > Ratios in number concentration between the 2 populations: peak et area

Summary of results



	Averaged mean diameter d _p (nm)	2* SD (nm)	Averaged mode diameter d _p (nm)	2* SD (nm)
SMPS	35.1	6.4	35.4	2.0
TEM	35.1	7.4	35.6	7.6
SEM	39.0	14.2	38.3	14.1
AFM	30.3	3.7	30.4	5.1

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OP

	First population			Second population				
	Averaged mean diameter d _p (nm)	2* SD (nm)	Averaged mode diameter d _p (nm)	2* SD (nm)	Averaged mean diameter d _p (nm)	2* SD (nm)	Averaged mode diameter d _p (nm)	2* SD (nm)
SMPS	44.0	4.0	44.2	5.3	85.0	4.1	83.1	3.4
TEM	42.9	9.0	43.7	11.9	86.3	12.3	88.1	12.0
SEM	46.6	15.1	47.0	13.8	89.8	20.1	91.1	19.8
AFM	36.2	7.1	39.2	6.8	80.2	5.0	81.0	5.3

Comparable results by techniques: validation of PSD characterization protocols

Comparable results between techniques :



implementation of different techniques : # diameters types (mobility, height, ...)

Spherical particles (equivalence of diameters)

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Conclusions



- Development and validation of generation protocols of 2 nano-aerosols types
 : OP and DP isolated ariborne nanoparticles (non-agglomerated)
- Development of sampling protocols for off-line measurements by 2 methods (filtration and et electrostatic precipitation) on appropriate supports (grids, filters and MICA plates)
- Development and validation of procedures for the size distribution characterization of SiO₂ airborne nanoparticles by on-line (SMPS) and off-line (MEB, MET et AFM) techniques: mean and mode diameters
- Interlaboratory comparison with metrological approaches (metrological traceability, calibration, and evaluation of the measurement uncertainty)

Recommendations



IMPACT of the VAMAS project



To provide measurements protocols accurate, reliable and robust and to give recommendations (scientific community, industry, legislative and regulatory authorities, etc.).

To answer some needs

- → To perform reliable toxicology studies,
- ➡ Quality control in industry and monitoring
- To provide Internationally harmonized measurement procedures for spherical airborne nanoparticles characterization for organizations in charge of standardization (CEN, ISO) in order to disseminate consensual and applicable standards for the size characterization of airborne nanoparticles

→ Transfer of this work in standardization committees (AFNOR, ISO):

Submission by AFNOR of a New Work Item Proposal for a project of International Standard (IS) « On-line/off-line techniques for characterizing size distribution of airborne nanoparticle population »



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Publications and Communications



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RESEARCH PAPER

Size characterization of airborne SiO₂ nanoparticles with on-line and off-line measurement techniques: an interlaboratory comparison study

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Abstract Results of an interlaboratory comparison on size characterization of SiO₂ airborne nanoparticles using on-line and off-line measurement techniques are discussed. This study was performed in the framework of Technical Working Area (TWA) 34—"Properties of Nanoparticle Populations" of the Versailles Project on Advanced Materials and Standards (VAMAS) in the project no. 3 "Techniques for characterizing size distribution of airborne nanoparticles". Two types of nano-aerosols, consisting of (1) one population of nanoparticles with a mean diameter between 30.3 and 39.0 nm and (2) two populations of non-agglomerated nanoparticles with mean diameters between, respectively, 36.2–46.6 nm and 80.2–89.8 nm, were generated for characterization measurements. Scanning mobility particle size spectrometers (SMPS) were used for on-line measurements of size distributions of the produced nano-aerosols. Transmission electron microscopy, scanning electron microscopy, and atomic force microscopy were used as off-line measurement



* NPLI, NPL and NIST were involved in this project but they didn't participate in the round robin test.



By our knowledge, it would be interesting to work on more complex particles (CNT,...)

To work on the development of procedures internationally harmonized with metrological approach to the other relevant parameters identified by the ISO TC 229 "Nanotechnology" and the OECD (Organisation for Economic Co-operation and Development)

Surface area, shape, surface charge, aggregation/agglomeration state, chemical composition (crystallinity, purity/impurity, global chemical composition), surface chemistry solubility/dispersibility







Thank you for your attention

